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An Integrated Laser Approach for Fiber Sensor Embedding in Metal Parts for Nuclear Energy Applications

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Motivation





- 3D Printing: A major fabrication approach for energy, infrastructure, aerospace
 - Special parts fabricated at 1000 per year
 - Large size (up to 5 meters)
 - Highly flexible in building materials
 - High Value added
 - Can we embed distributed fiber sensors to make SMART PARTS???
 - High-res strain measurements (1-cm)
 - Distributed acoustic and vibration
 - Temperature
 - Corrosion
 - Condition-based Maintenance





A Multi-Step Process



Embedded Sensors

AM Processes









- Embed distributed fiber sensors using additive manufacturing.
 - Direct metal laser sintering
 - Laser-energized net shaping
 - Wire-arcing (Smart parts as large as 1.5-meter)
 - Ultrasonic additive manufacturing
 - Fiber sensor packaging using glass sealants
- Sensor-enabled digital twin modeling.
- New fiber and metal coating with compatible thermal expansion coefficients (TECs)
- Demonstration of multi-parameter measurements in radiation environments
 - Instrumentation & algorithm developments.
 - Demonstration of high-frequency vibration measurements.
- Irradiation test of sensor embedded by AM.
- Fundamental challenges/limitation of sensor-embedding using AM and partial solutions.
- Impacts to other fields.





Vertically Integrated Sensor Fabrication Capability







Reel-to-reel fiber writing setup

- 180-fs laser.
- Fabrication of up to 1km of fibers.
- Point-by-point writing: Flexible.
- Through fiber coating fabrication.
- FBG, distributed, IFPI.
- High-T stable distributed sensors.
- Sapphire and silica fibers



Deep UV Sensing Fiber Fabrication

- Standard telecom fiber.
- One-shot UV phase mask writing
- 10-km continuous sensing fiber
- Draw-tower free
- Sensing fiber cost ~\$0.1-\$1.0 per meter (competition: \$10-30/m)
- Joint pending patent with Corning





Reel-to-Reel Sensor Fabrication









High-Temperature Stable Multiplexed Fiber Sensors







- Up to 25 high-temperature stable FBG array can be fabricated in hydrogen-resistant optical fibers.
- Packaged sensors in 316H SS tubing with polymer coating removed.
- Each sensor are pre-annealed and calibrated.
- Armored cable lead for field deployments.
- Packaged fibers can be repeated heated with consistent performance.







Robust Demodulation Algorithm



 $T = T_o + [A(\lambda - \lambda_o)^3 + B(\lambda - \lambda_o)^2 + C(\lambda - \lambda_o) + D]$

- Demodulation algorithm key for sensor success.
- Four demodulation algorithm explored for accurate and reliable demodulations (avoid "peak jump").
- Occasionally demodulation of FBG peak jumps are the issue (a sudden temperature change up to 8C).
- Computationally efficient and robust algorithm is needed to remove "peak fitting jump".

High-Temperature FBG Sensor Instruments



- Fully-integrated instrument (8, 16, 32, 64 channels)
- USB, Ethernet, wireless data communications.
- 5-kHz sampling rate (over total channel #).

The key is the algorithm!

- Three algorithms to ensure accurate sensor demodulation.
- Interrogate both FBG and IFPI arrays.
- Background data screening and validation.
- Can simultaneously interrogate up to 1280 point sensors.
- The world's first fully calibrated fiber sensors (Guaranteed at up to 650C).
- Aiming for full calibration at 850C.
- Made in Pittsburgh.







Field Test: Molten Salt Circulation Loop





- Completed immune to EM noises
- Radiation harden
- Straightforward calibration.
- One-fiber, 20 sensors vs. 40 lead wires 20 sensors.







Radiation-Harden Sensors



Advanced Methods for Manufacturing





Sensor Embedding in Metal Parts



- Enable energy users for rapid and straightforward sensor deployments
- Three sensor packaging technique developed for fiber sensor embedding in metal structures
- Applicable for a wide range of temperature ranges.







Wire-Arcing





Protection and Managing TEC Mismatch







- E-beam evaporation coating: 50-nm W glue layer (TEC ~ 3.4 ppm/C).
- Electroplating of Invar-36 protective coating: 400 800 μm (TEC ~ 0.5 ppm).
- Electroplating in a 3D printed plastic mold to minimize residual strain.
- Significant improvement in slippage temperatures.
- Still challenging to reach PWR operational temperatures.





New Specialty Fiber with high TEC – with Corning





 $TEC(GeO_2) = [5.5 + 115.2 \times (GeO_2 mol\%)] \times 10^{-7}$

- 3% Ge-doped fiber core to maintain same thermal optical coefficient
- Fused silica trench to ensure optical guiding
- 40% of Ge-doped silica outer cladding to increase TEC
- Successful fabrication of FBG fiber sensors
- TEC experimental measured by an IFPI sensors





Standard Fiber: $\Delta L/L = 0.55 \times 10^{-6} T$ <u>New fiber: $\Delta L/L = 1.45 \times 10^{-6} T$ </u>





Sensor-Fused AM Process – Metal Process





Sensor Fused AM Process

- High resolution real-time T & με measurements
- Design proper structures to embed sensors without disturbing AM process and part itself
- Real-time measurements to study AM process itself
- Post-process monitoring to study residual strain formation and relaxation.
- Compare, correct, and validate DT



Temperature Measurement by Embedded Sensors

The simulated global temperature profiles of the LENS

- (a) upon the completion of the deposition
- (b) 0.5s after the deposition process.
- Measured results by fiber sensors are shown in (c)-(e).





Strain Measurements vs. Simulation









Hermetical Sensor Embedding Using Glass Sealants





- Wide selection of sealant materials: glass and ceramics
- TEC of glass sealant ~ 5ppm/C right in the middle between silica fiber and metal.
- Hermetical bonding on metals enable pressure boundary penetration.
- Rapid process possible
- High-T application possible.
- Packaged sensor size > 6-mm diameter OD







Hermetical Sensor Embedding Using Glass Sealants





Experimental Results 1305 (Strain sensor ---- Temperature rising - Temperature rising 1620 - Cooling down --- Cooling down Temperature sensor-1303.5 1617 --- Linear fitting ----Linear fitting Temperature sensor-2 Ap 1302.0 1615 1615 Εb e. 1300.5 1613 L = 0.0137T + 1298.05695L = 0.01672T + 1610.49977 $R^2 = 0.99771$ $R^2 = 0.9978$ 1610 1299.0 FP cavity (µm) 1611 -200 300 400 200 300 400 0 100 500 Temperature (°C) Temperature (°C) (b) (c) 300 980 - - - - Linear fitting 988 988.0 Δ cavity length = 1.65 μ m - Cavity change axial strain = $1675 \,\mu\epsilon$ Strain induced cavity change 987 986.5 T induced cavity change 985 Demodulated residual strain 4 986 085 (= 0.00943T + 984.25381 $R^2 = 0.99206$ 98 980 983 1000 2000 3000 4000 0 100 200 300 400 500 1500 2000 2500 3000 3500 4000 Time (s) Time (s) Temperature (°C) (a) (d) (e)

- Sealing process induced compressive strain
- Experiment match simulation: ~1500-2000 compressive strain
- Linear temperature response: non slippage
- Both FBG and IFPI sensors have been embedded





Hermeticity and High-Temperature Testing









Ultrasonic Metal Additive Manufacturing





Sensor Fused UAM process





- Fs-inscribed 2-mm long FBG through polyimide coating.
- Low processing temperature ~170C for aluminum.
- AL-6061 H18 aluminum foil.
- 4 kN downforce and 32 μm peak-to-peak scrubbing amplitude.
- **•** Repeated strain test, no slippage up to 5000 με.
- Up to 300C operation (short-term).





Telecom laser enable FBG Interrogation



- Wavelength tuning stitching
- Gas-cell wavelength reference
- High-speed interrogation possible
- Heterogeneous multi-core architectures: FPGA+ DSP
- Rapid sensor data demodulation via DSP
- Static wavelength variation better than $\pm 2pm$









High-Frequency Vibration Sensing



Laser Velocimeter Comparison 5kHz vibration





SAMM

Advanced Methods for Manufacturing

In Collaboration with Prof. Bajaj at Pitt: nbajaj@pitt.edu



Demodulation Algorithm and Interrogation Systems for NE I&C



Bunman Frequency Estimation





- 10× more efficient than Gaussian Peak Fitting.
- Robust algorithm avoid "jump"
- Easy implementation into DSP chips
- Dedicate sensor demodulation electronics developed
- Support up to 1MHz sampling rates for acoustic/vibration sensing
- **40-nε dynamic strain**
- 0.1C static measurement (temperature)
- Eight channels to support >200 sensor simultaneously





Rapid Demodulation Algorithm









Irradiation of Embedded Fiber Sensors

Carried out by Dr. Moinuddin Ahmed



- Irradiation at LANSCE (Los Alamos Neutron Science Center)
- Sensors were irradiated with neutron energy above 1.5 MeV
- Sensors were irradiated at room temperature and at 300 °C.
- Irradiation times were set at 2 hrs and 4 hrs



Fiber Sensor 7 ([emperature (°C)	1.5MeV Neutrons (n/cm²)	10MeV Neutrons (n/cm ²)
1	25	9.409E+0	9 4.682E+09
2	25	1.892E+1	0 9.416E+09
3	300	9.409E+0	9 4.682E+09
4	300	1.892E+1	0 9.416E+09





Irradiation of Embedded Fiber Sensors

Carried out by Dr. Moinuddin Ahmed

Sensor 2



Sensor 4

Sensor 1





Fiber Sensor	Temperature (°C)	1.5MeV Neutrons (n/cm ²)	10MeV Neutrons (n/cm ²)
	1 2	5 9.409E+	09 4.682E+09
	2 2	5 1.892E+	10 9.416E+09
	3 30	0 9.409E+	09 4.682E+09
	4 30	0 1.892E+	10 9.416E+09

sensor	wave bef	wave aft	wave diff (nm)	loss bef	loss aft	loss diff (dB)
1	1546.73	1546.79	-0.06	-6.958	-16.827	9.869
2	1553.39	1553.36	0.03	-7.993	-16.658	8.665
4	1551.11	1548.52	2.59	-10.713	-16.647	5.934







What is the Challenge?





Post-Fabrication Heat Treatments are Essential





https://www.mtixtl.com/CM-HIP-2.aspx

UAM for SS410 Yield Stress: As Fabricated: 137.5MPa Heat treated: 337.8MPa HIP process: 1120C, 100 MPa, 4 hours

WAAM for Inconel 718 Yield Stress: As Fabricated: 430 MPa Heat treated: 1040 MP Heat Treatment: Multi-step, 1300C, 6 hours

(J. Song, X. A. Jimenez, C. Russel, A.C. To, <u>https://doi.org/10.1038/s41598-023-46674-z</u>)

Without Post Heat Treatment?

- Drastically poorer mechanic properties.
- Prone to corrosion.
- No known sensors can withstand post-fabrication heat treatments.



A RT Post Processing Laser Shock Peening (LSP)











Solution Laser Shock Peening (LPS)

A room temperature post-treatment

- A room-temperature post-process is known to improve corrosion performance.
- Simple and can be robotically deployed.
- Introducing a surface with compressive strain go as deep as 5-mm.
- Compressive strain as much as 0.1%.
- <u>Widely applicable for all AM-embedded</u> <u>fiber sensors</u>









A RT Post Processing: Laser Shock Peening





- 0.5 mJ/pulse, 10 ns, YAG.
- 0.5 mm/s peening speed.
- Reach maximum compressive strain: 130με measured by embedded fiber sensors
- Maximum depth: 5-10 mm.
- Suitable for NE applications.

The sensor are embedded between 1.115m-1,18m









LSP: Improved Thermal Performance













- Many AM techniques can embed fiber sensors in metal parts.
 - LENS, DMLS, UAM, and Wire arcing.
 - No operational slippage temperature reached 800C.
 - Demonstration of temperature, strain, and vibration sensing.
 - Smart part withstand up to 20 MP pressure and through the pressure boundary.
- Innovated optical fibers and metal coating can improve performance.
- Fiber sensors can NOT withstand post-fabrication heat treatment.
- Laser shock peening can be a room-temperature alternative to post-fabrication heat treatment.
- Fiber sensor should be embedded within 10 mm? from the surface.
- Multi-step process.



Contribution to Other Fields

Additive Laser Integrated Systems for Analysis The World's Most Advanced Organ-on-a-Chip (OC) Devices

Breakthrough innovation

- Achieve complete flexibility in building materials.
- Free from drug molecule contamination.
- Nature 3D structures achieving complex and multifunctional chips.
- On-chip flow control integration of pump and valves!
- On-chip sensors embedding rich on-chip functions.
- Built-in sealing layer straightforward assembly and use minimize bio-contamination.
- Eliminate 80% of expensive off-chip instruments.





On-Chip Pump and Valves

- On-chip three-way valve and pump for complex liquid routing with no latency!
- Eliminated off-chip instruments.



Example: Injection of 20-60 µl drug without bubble using on-chip pump/valve





Embedding Sensors on-Chips

- Antibody functionalized polymer can be integrated on-chip.
- On-chip ELIZA, fluorescent, Raman, and flow measurements.



Successful Production of Pancreatic Islets using Induced Pluripotential Stem Cell (iPSc)



- Seven-day continuous cultures.
- Achieved 90% viability.
- Successful production and harness of iPSC derived pancreas islets.







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Collaboration Welcome!

